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Front Matter: Volume 8416

, "Front Matter: Volume 8416," Proc. SPIE 8416, 6th International Symposium on Advanced Optical Manufacturing and Testing Technologies: Advanced Optical Manufacturing Technologies, 841601 (16 October 2012); doi: 10.1117/12.2012104

SPIE.

Event: 6th International Symposium on Advanced Optical Manufacturing and Testing Technologies (AOMATT 2012), 2012, Xiamen, China

PROCEEDINGS OF SPIE

6th International Symposium on Advanced Optical Manufacturing and Testing Technologies

Advanced Optical Manufacturing Technologies

Li Yang
Eric Ruch
Shengyi Li
Editors

26–29 April 2012
Xiamen, China

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Volume 8416

Proceedings of SPIE 0277-786X, V.8416

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

6th International Symposium on Advanced Optical Manufacturing and Testing Technologies: Advanced Optical Manufacturing Technologies, edited by Li Yang, Eric Ruch, Shengyi Li, Proc. of SPIE Vol. 8416, 841601
© 2012 SPIE · CCC code: 0277-786/12/\$18 · doi: 10.1117/12.2012104

Proc. of SPIE Vol. 8416 841601-1

The papers included in this volume were part of the technical conference cited on the cover and title page. Papers were selected and subject to review by the editors and conference program committee. Some conference presentations may not be available for publication. The papers published in these proceedings reflect the work and thoughts of the authors and are published herein as submitted. The publisher is not responsible for the validity of the information or for any outcomes resulting from reliance thereon.

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Author(s), "Title of Paper," in *6th International Symposium on Advanced Optical Manufacturing and Testing Technologies: Advanced Optical Manufacturing Technologies*, edited by Li Yang, Eric Ruch, Shengyi Li, Proceedings of SPIE Vol. 8416 (SPIE, Bellingham, WA, 2012) Article CID Number.

ISSN: 0277-786X

ISBN: 9780819490988

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA

Telephone +1 360 676 3290 (Pacific Time) • Fax +1 360 647 1445

SPIE.org

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Contents

xiii	<i>Symposium Committee</i>
xv	<i>Introduction</i>
xvii	<i>AOMATT 2012 Sponsors</i>

INVITED SESSION

8416 02	Research on fabrication of mirror segments for E-ELT (Invited Paper) [8416-205] G. Yu, OpTIC Glyndwr Ltd. (United Kingdom); D. D. Walker, OpTIC Glyndwr Ltd. (United Kingdom), Univ. College London (United Kingdom), and Zeeko Ltd. (United Kingdom); H. Li, Univ. College London (United Kingdom)
8416 03	Development of a flexible and reliable numerical simulation for precision glass molding of complex glass optics (Invited Paper) [8416-35] F. Klocke, F. Wang, Y. Wang, G. Liu, O. Dambon, Fraunhofer Institute for Production Technology (Germany); A. Y. Yi, The Ohio State Univ. (United States)
8416 04	Asphere metrology using variable optical null technology (Invited Paper) [8416-204] C. Supranowitz, C. McFee, P. Murphy, QED Technologies, Inc. (United States)

SESSION 2-1

8416 05	Numerical simulation of temperature field and experimental inquiry of TC4 titanium alloy laser rapid forming [8416-1] Y. Lai, Shenyang Institute of Automation (China) and Graduate Univ. of Chinese Academy of Sciences (China); W. Liu, Shenyang Institute of Automation (China); Y. Kong, F. Wang, Shenyang Institute of Automation (China) and Graduate Univ. of Chinese Academy of Sciences (China); Y. Zhao, Shenyang Institute of Automation (China)
8416 06	Precision manufacturing of fused silica glass by combining bound-abrasive polishing with ultrasonic vibration [8416-53] Y. Li, Akita Prefectural Univ. (Japan) and Chengdu Fine Optical Engineering Research Ctr. (China); Y. Wu, Akita Prefectural Univ. (Japan); J. Wang, Q. Xu, Chengdu Fine Optical Engineering Research Ctr. (China); W. Yang, Y. Guo, Xiamen Univ. (China)
8416 07	A large ion beam figuring plant used for manufacturing astronomical telescope [8416-61] W. Guo, B. Liang, X. Cheng, Y. Zheng, Nanjing Institute of Astronomical Optics & Technology (China)
8416 08	Progresses in optical design and simulation optimization methods [8416-73] H. Liu, Q. Ding, National Key Lab. of Science and Technology on Fire Control (China); L. Zhou, Beijing Institute of Technology (China)

- 8416 09 **Supersmooth polishing with sub-angstrom roughness** [8416-75]
J. Wang, Changchun Institute of Optics, Fine Mechanics and Physics (China)
- 8416 0A **Lapping application research for touch screen glass using 3M fine grade Trizact diamond tile** [8416-94]
L. Zheng, 3M South China Technical Ctr. (China); T. K. Na, 3M R&D Ctr. (Singapore)
- 8416 0B **Novel method for fabricating steep aspheric mirrors** [8416-107]
Y. Shu, S. Li, X. Zuo, C. Song, Y. Wang, National Univ. of Defense Technology (China)

SESSION 2-2

- 8416 0C **An integrated approach for design, ultraprecision polishing, and measurement of freeform progressive lenses** [8416-102]
C. F. Cheung, L. B. Kong, L. T. Ho, S. To, B. Wang, K. T. Lai, The Hong Kong Polytechnic Univ. (Hong Kong, China)
- 8416 0D **Development of an externally pressurized bearing-rotor system for a five-axis ultraprecision machine tool used for optical manufacture and the static performance analysis of the externally pressurized bearing** [8416-47]
E. Qi, Z. Fang, T. Sun, J. Zhou, G. Hou, Harbin Institute of Technology (China)
- 8416 0E **Study on combination technology in off-axis asphere manufacture** [8416-500]
Y. Wang, S. Li, X. Peng, X. Nie, C. Song, National Univ. of Defense Technology (China)
- 8416 0F **Insights into effects of thermal annealing on optical properties of SiO₂ films** [8416-51]
Y. Jiang, Tongji Univ. (China) and Tianjin Jinhang Institute of Technical Physics (China); Y. Ji, Tianjin Jinhang Institute of Technical Physics (China) and Harbin Institute of Technology (China); H. Liu, D. Liu, L. Wang, C. Jiang, Tianjin Jinhang Institute of Technical Physics (China); Y. Yang, Tongji Univ. (China); D. Chen, Harbin Institute of Technology (China)
- 8416 0G **Study on UVC ultraviolet filter film** [8416-19]
Y. Kou, X. Fu, D. Liu, H. Zhu, H. Tang, Changchun Univ. of Science and Technology (China)

SESSION 2-3

- 8416 0H **Study on the synthesis and optical properties of polyurethane-imide** [8416-203]
L. D. Wang, Southeast Univ. (China) and Huainan Normal Univ. (China); T. Zhang, X.-Y. Zhang, R.-Z. Li, L.-N. Wang, S.-Q. Zhu, Southeast Univ. (China)
- 8416 0I **Illuminator design for small field ArF lithography system** [8416-145]
L. Wei, Y. Li, K. Liu, X. Liu, Beijing Institute of Technology (China)
- 8416 0J **Data filtering of optical freeform measurement based on a modified 2D cascaded approximating spline filter** [8416-109]
Q. Wang, X. Zhang, Y. Peng, F. Fang, Tianjin Univ. (China)

- 8416 OK **Evolution and control of optical thin film stress** [8416-206]
M. Fang, Shanghai Institute of Optics and Fine Mechanics (China); J. Li, Shanghai Institute of Optics and Fine Mechanics (China) and Graduate Univ. of Chinese Academy of Sciences (China); H. He, Z. Fan, Q. Xiao, Z. Y. Li, Shanghai Institute of Optics and Fine Mechanics (China)

POSTER SESSION

- 8416 OL **An on-line condition monitoring and monitoring point position visual system in grinding** [8416-11]
W. Han, W. Yang, Y. Guo, T. Jiang, C. J. Wang, Xiamen Univ. (China)
- 8416 OM **High performance narrow band-pass filter for the NIR/MWIR range** [8416-69]
X. Su, W. Wu, K. Yan, F. Chen, C. Meng, LuoYang Optoelectro Technology Development Ctr. (China)
- 8416 ON **Tri-rotors movement in computer controlled optical surfacing** [8416-83]
X. Chen, P. Guo, J. Ren, Soochow Univ. (China)
- 8416 OO **The research on making large-size aspherical mirrors by vacuum evaporation technique** [8416-207]
J. Wang, Nanjing Institute of Astronomical Optics & Technology (China)
- 8416 OP **Polishing large-aperture mirror using ultraprecise Bonnet and PSD result analysis** [8416-98]
W. Wang, M. Xu, Fudan Univ. (China); H. Li, Harbin Institute of Technology (China), Univ. College London (United Kingdom), and OpTIC Glyndwr Ltd. (United Kingdom); G. Yu, OpTIC Glyndwr Ltd. (United Kingdom)
- 8416 OQ **Optimum parameters for precision compression molding of spherical glass-lens arrays** [8416-7]
J. Lu, J. Wang, M. Xu, H. Zhang, Fudan Univ. (China)
- 8416 OR **Manufacturing technology of lightweight mirror for space optics** [8416-9]
Y. Chen, J. Xie, Changchun Institute of Optics, Fine Mechanics and Physics (China)
- 8416 OS **Design and manufacture of anti-IR thin films for resin lens** [8416-15]
J. Chen, H. Feng, H. Chen, C. Hu, Y. Li, Wenzhou Medical College (China)
- 8416 OT **An adaptive interpolation method for tool path generation based on iso-photo for large scale wedge /aspheric lens element grinding** [8416-5]
N. Zhang, Xiamen Univ. (China) and Zhejiang Univ. of Technology (China); F. Yang, D. Zhang, M. Chen, Z. Wang, Y. Guo, Xiamen Univ. (China)
- 8416 OU **Goniometer system of vehicle anti-tank missile design** [8416-208]
M. Yan, X. Shan, H. Zhao, Changchun Institute of Technology (China)

- 8416 0V **Influence of substrate rotating on the microstructure and surface morphology of Ge and Si thin films** [8416-21]
H. Luo, Shanghai Institute of Technical Physics (China) and Graduate Univ. of Chinese Academy of Sciences (China); D. Liu, Shanghai Institute of Technical Physics (China); X. Yin, Shanghai Institute of Technical Physics (China) and Graduate Univ. of Chinese Academy of Sciences (China)
- 8416 0W **Study on the applications of high-precision optical wedge machining, assembling, and adjustment technologies** [8416-30]
Y. Su, R. Guo, J. Shi, Y. Zhang, F. Zhang, X. Liu, H. Zhao, Xi'an Institute of Applied Optics (China)
- 8416 0X **High efficient and ultra-precision machining of large scale SiC plane reflectors** [8416-24]
R. Guo, Y. Su, C. Chen, Y. Zhang, F. Zhang, X. Liu, Xi'an Institute of Applied Optics (China)
- 8416 0Y **Effects analysis of large area polishing tool on aspheric surface quality** [8416-33]
Y. Zhang, F. Zhang, J. Yan, Y. Su, R. Guo, X. Liu, Xi'an Institute of Applied Optics (China)
- 8416 0Z **Fabrication and measurement of toric lens** [8416-34]
X. Liu, Y. Su, H. He, Y. Zhang, R. Guo, F. Zhang, Xi'an Institute of Applied Optics (China)
- 8416 10 **Aspheric surface profile effects analysis in polishing with ballonet polishing tool** [8416-25]
F. Zhang, Y. Zhang, Xi'an Institute of Applied Optics (China); W. Kang, Xi'an North Optoelectronic Science and Technology Defense Co. Ltd. (China); Y. Su, C. Chen, X. Liu, Xi'an Institute of Applied Optics (China)
- 8416 11 **Design and fabrication of high efficiency diffuser film based on laser speckle** [8416-23]
Y. Li, X. Ren, S. Liu, Xiamen Univ. (China)
- 8416 12 **Bonnet polishing high-slope aspheric surface** [8416-108]
J. Zhang, Changchun Institute of Optics, Fine Mechanics and Physics (China)
- 8416 13 **Study on range selection of key parameters in bonnet polishing using FEA** [8416-10]
R. Pan, Z. Wang, D. Zhang, C. Wang, Y. Xie, Y. Guo, Xiamen Univ. (China)
- 8416 14 **Research on a two ball lens system POF connector** [8416-54]
Z. Huang, G. Liu, Z. Ren, L. Zeng, Q. Wan, Jiangxi Science and Technology Normal Univ. (China)
- 8416 15 **Simulation of high-resolution linear CCD satellite image** [8416-92]
R. Zhang, S. Luo, G.-W. Jiang, T. Jiang, Information Engineering Univ. (China); M. Sun, People's Liberation Army (China)
- 8416 16 **Study on object-oriented petri net in modeling for infrared dome optical manufacturing** [8416-45]
H. Wang, Northwestern Polytechnical Univ. (China) and LuoYang Optoelectro Technology Development Ctr. (China); H. Chen, LuoYang Optoelectro Technology Development Ctr. (China)
- 8416 17 **Custom design of aspherical RGP contact lens** [8416-16]
C. Hu, Y. Li, J. Chen, Y. Wang, S. Chen, H. Chen, Wenzhou Medical College (China)

- 8416 18 **Study on the optical manufacture and testing methods of a refractive-reflective meniscus primary mirror** [8416-93]
J. Kang, Changchun Institute of Optics, Fine Mechanics and Physics (China) and Graduate Univ. of Chinese Academy of Sciences (China); B. Xuan, Changchun Institute of Optics, Fine Mechanics and Physics (China); J. Xie, Graduate Univ. of Chinese Academy of Sciences (China)
- 8416 19 **Key technologies for diamond turning of non-rotational symmetrical micro-structured surfaces** [8416-43]
J. Zhou, T. Sun, G. Hou, E. Qi, Harbin Institute of Technology (China)
- 8416 1A **An efficient CNC polishing technology of aspherical parabolic cylindrical lens** [8416-64]
Q. Huang, H. Chen, S. Hu, LuoYang Optoelectro Technology Development Ctr. (China)
- 8416 1B **Effects of structured surface errors on MTF of off-axis TMA system** [8416-13]
X. Zeng, Changchun Institute of Optics, Fine Mechanics and Physics (China) and Graduate Univ. of Chinese Academy of Sciences (China); F. Yan, X. Zhang, Changchun Institute of Optics, Fine Mechanics and Physics (China)
- 8416 1C **The study on errors of prisms of a quarter-width camera system** [8416-138]
P. Xie, L. Xing, Changchun Institute of Optics, Fine Mechanics and Physics (China)
- 8416 1D **Study on the control of surface roughness in single point diamond turning** [8416-56]
H. Xu, X. Zhang, Fudan Univ. (China); M. Xu, Fudan Univ. (China) and Modern Advanced Ultra-Precision Manufacturing Ctr. (China); X. Li, Modern Advanced Ultra-Precision Manufacturing Ctr. (China)
- 8416 1E **Magnetic medium assistant polishing technology and experiments** [8416-135]
W. Deng, L. Zheng, F. Zhang, Changchun Institute of Optics, Fine Mechanics and Physics (China)
- 8416 1F **Aging effect of optical properties on SiO₂ films grown on Si substrates by ion beam sputtering** [8416-77]
Y. Ji, Harbin Institute of Technology (China) and Tianjin Jinhang Institute of Technical Physics (China); H. Liu, Tianjin Jinhang Institute of Technical Physics (China); Y. Jiang, Tianjin Jinhang Institute of Technical Physics (China) and Tongji Univ. (China); D. Liu, L. Wang, C. Jiang, Tianjin Jinhang Institute of Technical Physics (China); R. Fan, D. Chen, Harbin Institute of Technology (China)
- 8416 1G **Design and manufacture of high reflective coatings deposited on metal substrate** [8416-101]
L. Wang, H. Liu, Y. Jiang, C. Jiang, Y. Ji, Tianjin Jinhang Institute of Technical Physics (China)
- 8416 1H **Multi-channel optical telescope with free-form surface splitters** [8416-89]
X. Li, M. Xu, Fudan Univ. (China); X. Ren, Jining Medical Univ. (China)
- 8416 1I **Optimization of freeform cylindrical lens in Czerny-Turner spectrometer system to correct the astigmatism by using user defined error function** [8416-22]
B. Qu, G. Xia, F. Yu, Zhejiang Univ. (China)

- 8416 1J **Analysis and optimization of tooth shapes of roll stampers for optical micro-structured array imprinting** [8416-131]
S. Yang, X. Zhang, M. Xu, Fudan Univ. (China)
- 8416 1K **Eight-axis-polishing machine for 2 m off-axis aspheric optics** [8416-209]
H.-G. Rhee, H.-S. Yang, I.-K. Moon, H. Kihm, J.-H. Lee, Y. Ghim, Y.-W. Lee, Korea Research Institute of Standards and Science (Korea, Republic of)
- 8416 1L **Investigation on the MTF for the large-aperture long focal length TDICCD camera** [8416-57]
J. Xin, Beijing Institute of Space Mechanics and Electricity (China)
- 8416 1M **Correction of full spatial frequency errors with ion beam figuring** [8416-104]
Y. Gu, Changchun Institute of Optics, Fine Mechanics and Physics (China) and Graduate Univ. of Chinese Academy of Sciences (China)
- 8416 1N **Analysis of chemical polishing for optical elements** [8416-88]
L. Jiao, Y. Jin, N. Lin, T. Liu, Y. Tong, D. Wu, C. Hui, Tianjin Jinhang Institute of Technical Physics (China)
- 8416 1O **Ultra-precision surface polishing using ion beam figuring** [8416-31]
Y.-S. Ghim, S.-J. You, H.-G. Rhee, H.-S. Yang, Y.-W. Lee, Korea Research Institute of Standards and Science (Korea, Republic of)
- 8416 1P **Design of primary mirror supporting structure and lightweight of space camera** [8416-154]
C. Zhu, T. Xu, Tongji Univ. (China); S. Liu, B. Yang, Y. Liu, Shanghai Institute of Technical Physics (China)
- 8416 1Q **Anti-reflection coating on calcium fluoride substrate using ion-assisted deposition** [8416-80]
Y. Zhang, J. Fan, H. Xu, Institute of Optics and Electronics (China)
- 8416 1R **Research on spectral calibration for hyper-spectral imager** [8416-200]
Y. Guo, Y. Li, X. Zong, Beijing Institute of Space Mechanics and Electricity (China)
- 8416 1S **Rigidity controllable polishing tool based on magnetorheological effect** [8416-41]
J. Wang, Institute of Optics and Electronics (China) and Graduate Univ. of Chinese Academy of Sciences (China); Y. Wan, C. Shi, Institute of Optics and Electronics (China)
- 8416 1T **Application of two-sided prisms in pyramid wavefront sensor** [8416-71]
J. Wang, Southwest Univ. of Science and Technology (China) and Institute of Optics and Electronics (China); C. Guan, Institute of Optics and Electronics (China)
- 8416 1U **Laser beam shaping and packaging system** [8416-85]
D. Luo, B. Zhao, Institute of Semiconductors (China)
- 8416 1V **The exploration of cloud manufacturing service mode for high power laser optical elements** [8416-132]
J. Wang, J. Wang, Y. Tao, H. Li, W. Li, L. Jiang, Institute of Computer Application (China)
- 8416 1W **Effect of hydrodynamic pressure on ultraprecision grinding** [8416-210]
Y. Hwang, H.-J. Kim, J.-H. Kim, Korea Photonics Technology Institute (Korea, Republic of)

- 8416 1X **Machining simulation of off-axis parabolic hexagonal mirrors** [8416-36]
X. Feng, Institute of Optics and Electronics (China) and Graduate Univ. of Chinese Academy of Sciences (China); B. Fan, Institute of Optics and Electronics (China)
- 8416 1Y **Study on the best arrangement of sensors used in the deformation measurement of active lap based on genetic algorithm** [8416-38]
H. Zhao, Institute of Optics and Electronics (China) and Graduate Univ. of Chinese Academy of Sciences (China); X. Li, Z. Zeng, Institute of Optics and Electronics (China)
- 8416 1Z **Introduction and manufacturing of oblate spheroid mirror** [8416-211]
D. Li, L. Yuan, L. He, B. Wang, Nanjing Institute of Astronomical Optics & Technology (China)
- 8416 20 **Ultraprecision optical fabrication on fused silica** [8416-76]
J. Wang, Changchun Institute of Optics, Fine Mechanics and Physics (China)
- 8416 21 **Generation of radially polarized femtosecond pulse beam with a polarization plates array** [8416-130]
J. Qi, National Univ. of Defense Technology (China) and Military Academy of PLA (China); Y. Nie, X. Wang, J. Liao, J. Liu, J. Yang, H. Jia, X. Li, National Univ. of Defense Technology (China)
- 8416 22 **Mathematical model for active lap to achieve unsymmetrical fabrication** [8416-65]
H. Liu, Institute of Optics and Electronics (China) and Graduate Univ. of Chinese Academy of Sciences (China); Z. Zeng, F. Wu, B. Fan, Institute of Optics and Electronics (China)
- 8416 23 **A study of new optimization of LED projector with high efficiency and contrast** [8416-212]
Y.-C. Fang, C.-A. Chen, National Kaohsiung First Univ. of Science and Technology (Taiwan); C.-M. Tsai, Kun Shan Univ. (Taiwan); C.-T. Yen, National Formosa Univ. (Taiwan); H.-Y. Wu, C.-H. Chu, National Kaohsiung First Univ. of Science and Technology (Taiwan)
- 8416 24 **Preform rod feeding module of the optical fiber drawing tower and its algorithm design based on STM32** [8416-156]
T. Zhang, Z. Fan, G. Liu, T. Geng, X. Li, Harbin Engineering Univ. (China)
- 8416 25 **Reconstructing in laser wavelength scanning interference test of aspheric surface** [8416-202]
L. Li, Institute of Optics and Electronics (China) and Sichuan Univ. (China); W. Zhao, Institute of Optics and Electronics (China); X. Su, Sichuan Univ. (China); F. Wu, B. Fan, Institute of Optics and Electronics (China)
- 8416 26 **Experimental study of grinding removal efficiency in optical processing for using NC manipulator** [8416-91]
W. Zhang, Institute of Optics and Electronics (China) and Graduate Univ. of Chinese Academy of Sciences (China); Z. Zeng, F. Wu, B. Zhuo, Institute of Optics and Electronics (China)
- 8416 27 **A new method of calibrating the spatial coordinate coherence of shadowgraph-taking camera stations at the long distance with PSD** [8416-58]
J. Li, X. Wang, H. Shen, R. Zhu, Y. Huang, S. Rong, Y. Bian, Nanjing Univ. of Science and Technology (China)

- 8416 28 **Ultraprecision turning experiments of micro-holes on GDP capsule** [8416-29]
G. Li, Y. Huang, W. Tong, K. Du, Research Ctr. of Laser Fusion (China)
- 8416 29 **Elimination of the imprinting effect of the lightweight aspheric polished by CCAI technology using immersed inflation** [8416-79]
X. Zhong, Q. Xu, B. Fan, J. Zhou, Institute of Optics and Electronics (China)
- 8416 2A **Two-dimensional of uniform irradiation on target with the use of the concentricity deviation lens arrays focus system of variable focus length** [8416-72]
J. Zheng, Dalian Nationalities Univ. (China) and Dalian Univ. of Technology (China); Q. Yu, Dalian Univ. of Technology (China); Y. Lu, Dalian Nationalities Univ. (China); S. Guan, Dalian Nationalities Univ. (China) and Dalian Univ. of Technology (China); B. Dong, Dalian Nationalities Univ. (China)
- 8416 2B **Effects of colloid rheological characters in ultra-smooth polishing by nanoparticle colloid jet machining** [8416-90]
X. Song, Lanzhou Univ. of Technology (China); Y. Zhang, F. Zhang, Harbin Institute of Technology (China)
- 8416 2C **Comparative analysis of three-position measurement technology and multi-positions average measurement technology** [8416-84]
P. Yang, Guiyang Univ. (China) and Institute of Optics and Electronics (China); F. Wu, X. Hou, Institute of Optics and Electronics (China)
- 8416 2D **Research on SiO₂ film laser damage threshold** [8416-42]
T. Wang, L. Yang, Xi'an Technological Univ. (China)
- 8416 2E **Thermal-structural-optical analysis for the lens of high-precision interferometer** [8416-40]
J. Zhang, Y. Wu, F. Wu, Institute of Optics and Electronics (China)
- 8416 2F **Optical aligning and measuring methods for large aperture optical system** [8416-110]
X. Zhang, R. Wei, J. Duan, J. Yang, H. Li, X. Hou, Xi'an Institute of Optics and Precision Mechanics (China)
- 8416 2G **Noise factor of microchannel plate with ion barrier film** [8416-99]
S. Liu, Science and Technology on Low-Light-Level Night Vision Lab. (China) and Institute of High Energy Physics (China); F. Shi, Z. Li, Y. Zhu, N. Zhang, Science and Technology on Low-Light-Level Night Vision Lab. (China); Y. Gu, J. Sun, X. Cong, H. Zhao, J. Pan, Y. Qian, S. Zheng, B. Chang, Nanjing Univ. of Science and Technology (China)
- 8416 2H **Kinematical analysis of one-axis polisher acting on spherical mirror** [8416-63]
L. Xu, J. Ding, Z. Ma, Q. Chen, Xi'an Institute of Optics and Precision Mechanics (China)
- 8416 2I **Manufacturing of glass-based optical power splitter by ion-exchange method** [8416-46]
Y. Xiao, J. Yang, M. Wang, Zhejiang Univ. (China)
- 8416 2J **Design and experiments of a novel micro-displacement mechanism based on piezoelectricity actuator** [8416-32]
Y. Li, Harbin Institute of Technology (China) and Heilongjiang Univ. of Chinese Medicine (China); J. Wang, W. Zhai, S. Dong, G. Li, Harbin Institute of Technology (China)

- 8416 2K **Self-generated magnetic fields in the relativistic laser-plasma interaction** [8416-95]
A. Abudurexiti, Xinjiang Univ. (China)
- 8416 2L **Preferential sputtering of Ar ion processing SiO₂ mirror** [8416-28]
G. Duan, Institute of Optics and Electronics (China) and Graduate Univ. of Chinese Academy of Sciences (China); T. Xing, Y. Li, Institute of Optics and Electronics (China)
- 8416 2M **Optimization of the edge extension in dwell time algorithm for ion beam figuring** [8416-37]
L. Shu, Institute of Optics and Electronics (China) and Graduate Univ. of Chinese Academy of Sciences (China); F. Wu, C. Shi, Institute of Optics and Electronics (China)
- 8416 2N **Hybrid refractive/diffractive optical system design for light and compact uncooled longwave infrared imager** [8416-68]
H. Wang, Northwestern Polytechnical Univ. (China) and Xi'an Institute of Optics and Precision Mechanics (China); Y. Bai, Institute of Optics and Electronics (China); J. Luo, Northwestern Polytechnical Univ. (China)
- 8416 2O **A new numerical calculation method for the characteristics of hydrostatic slide** [8416-20]
G. Hou, T. Sun, J. Zhou, E. Qi, Harbin Institute of Technology (China)
- 8416 2P **Research on theoretical analysis of active fluid jet polishing** [8416-213]
T. Sun, L. Sun, F. Wang, S. Liu, Dalian Institute of Chemical and Physics (China)
- 8416 2Q **Fabrication of supersmooth optical elements with low surface and subsurface damage** [8416-159]
G. Zhan, Z. Shen, B. Ma, X. Wang, Z. Wang, Tongji Univ. (China); H. Liu, Y. Ji, Tongji Univ. (China) and Tianjin Jinhang Institute of Technical Physics (China)

Author Index

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Introduction

The 6th International Symposium on Advanced Optical Manufacturing and Testing Technology (AOMATT) was held 26–29 April 2012 at the Xiamen International Conference Center, Xiamen, China.

AOMATT 2012 was kicked off on April 26 with a formal opening ceremony. The ceremony started with the introduction of VIP guests, symposium chairs, and conference chairs, followed by opening speeches by Prof. Liwei Zhou, AOMATT 2012 Symposium Chairman, Prof. Bin Xu, Vice President of IOE, sponsor of AOMATT2012, and Dr. H. Philip Stahl, Vice President of SPIE, technical cosponsor of AOMATT2012. Plenary sessions started immediately after the conclusion of the opening ceremony. There were a total of 10 plenary presentations: Dr. H. Philip Stahl, 2012 SPIE Vice President and NASA Marshall Space Flight Center (USA); Prof. Hiroki Kuwano, 2012 President of Japanese Mechanics Society and Director of Micro/Nano Center, Tohoku University (Japan); Dr. Fritz Klocke, President of Fraunhofer Institute for Production Technology IPT (Germany); Dr. James Burge, Professor of Optical Sciences and Astronomy at the University of Arizona (USA); Dr. Eric Ruch, SAGEM (France); Dr. Tilmann Heil, Director of System Engineering, Carl Zeiss SMT GmbH (Germany); Prof. W. B. Lee, Professor of Manufacturing Engineering and Director of Advanced Technology Manufacturing Research Centre, Hong Kong Polytechnic University; Dr. Fengzhou Fang, Professor of Precision Measurement Technology and Instruments at Tianjin University (China); Prof. Shengyi Li, Professor of Mechatronics and Automation at the National University of Defense Technology (China). More than 1,000 people attended the opening ceremony and full-day plenary sessions.

More than 1,000 abstracts were submitted to AOMATT2012, and from these about 500 oral and poster papers were selected. Oral papers were presented in 8 parallel conferences on April 27 and 28. An all-symposium poster session was held in the afternoon of April 28. All of the parallel conference sessions and the poster session were well attended. Authors and attendees had active discussions and exchange of ideas throughout the symposium. Many papers presented cutting-edge research and development work in optical design, manufacturing, and testing. The success of AOMATT2012 continued the tradition of focus and excellence of this biannual international topical symposium in China.

We would like to express our sincere appreciation to COS - The Chinese Optical Society, IOE - Institute of Optics and Electronics, Chinese Academy of Sciences, and SPIE for sponsoring and supporting AOMATT2012. We want to thank all authors and participants for their contributions to the symposium and sharing their research with colleagues around the world. The 7th AOMATT is planned for 2014.

We look forward to seeing everyone at AOMATT2014. Please watch for the Call for Papers and symposium announcements on SPIE and IOE web sites.

Li Yang
Jinxue Wang
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